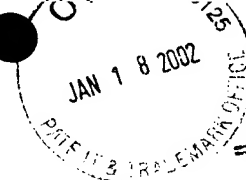




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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231 on October 18, 2001.



*Rosalie Ann Centeno*  
Rosalie Ann Centeno, Secretary

In the application of Peter Dress, et al  
Serial Number: 09/913,986  
Filing Date: August 16, 2001  
For: METHOD AND APPARATUS FOR TREATING SUBSTRATES

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Assistant Commissioner for Patents  
Washington, DC 20231

INFORMATION DISCLOSURE STATEMENT

In accordance with 37 CFR § 1.56, Applicant wishes to call the attention of the Examiner to the following reference(s):

- 1) EP 0 711 108 B1
- ✓ 2) DE 195 45 573 A1
- ✓ 3) DE 92 18 974 U1
- 4) 5,042,421 (17)
- ✓ 5) DE 40 24 642 C2
- ✓ 6) JP 04146615
- 7) 5,445,677 W
- ✓ 8) JP 56070634
- ✓ 9) JP 05084460
- ✓ 10) IBM "Upside-Down Resist Coating of Semiconductor Wafers"

*6*

The relevance of references 1-3 have been discussed in the instant specification on page 1 and therefore need no further discussion.

The relevance of references 4 and 5 have been discussed in the instant specification on page 2 and therefore also need no further discussion.

References 6 - 10 have been cited in the International Search Report and are submitted to provide the Examiner easy access to said references.

Copies of all listed documents are submitted herewith along with the form PTO-1449.

Consideration of the foregoing in relation to this application is respectfully requested.

Respectfully submitted,



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for the Applicant

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Enclosures